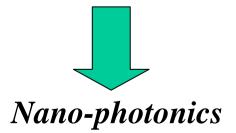
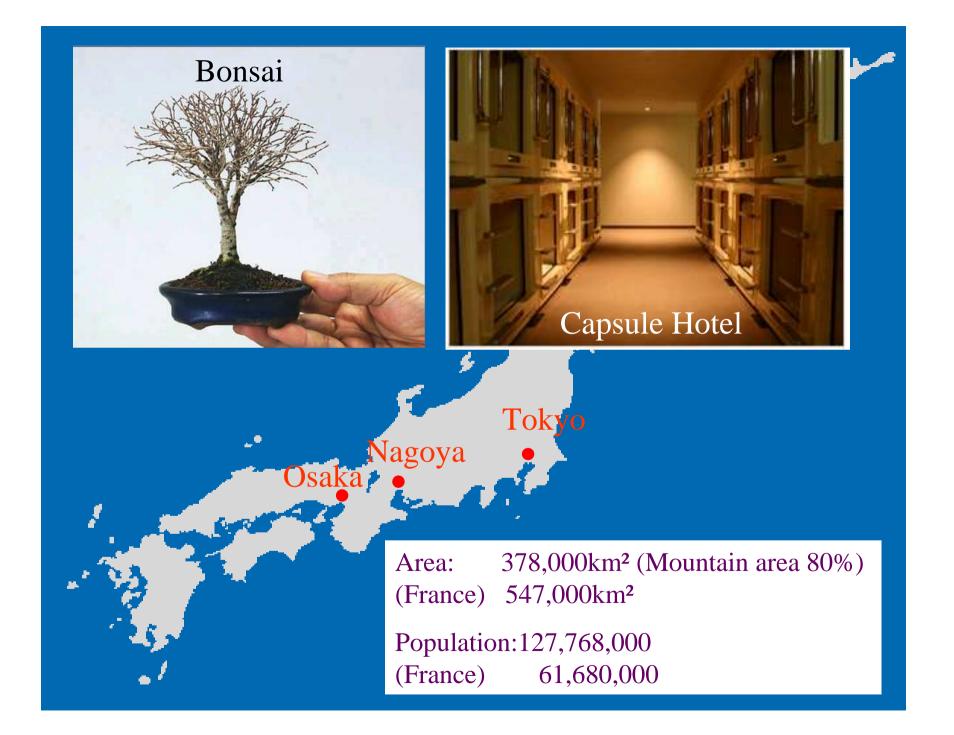
Nano-photonics and Plasmonics in Japan

Kazuo Tanaka (Gifu University) Yanagido 1-1, Gifu Japan 501-1193

Near-field optics, Nano-optics, Plasmonics, Nano-plasmonics,

Nanophotonics



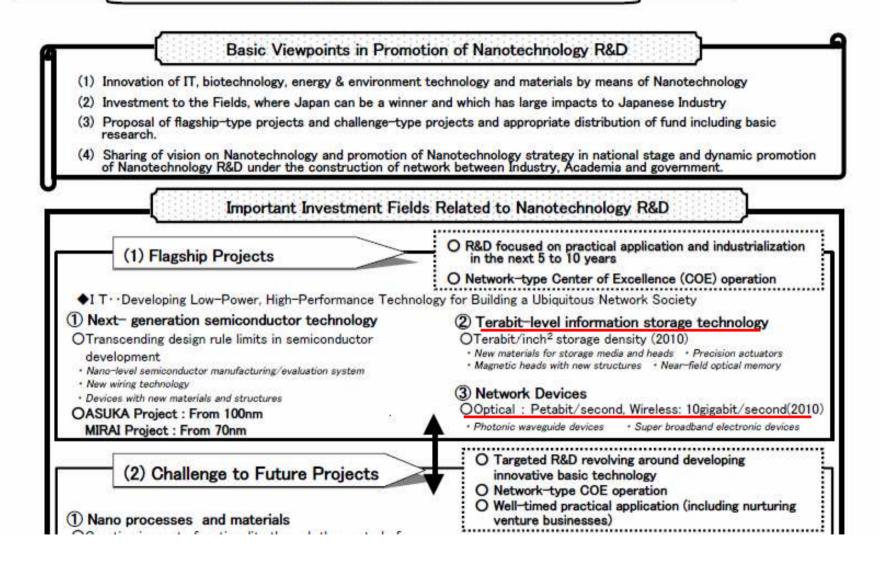


A Brief History of Nanotechnology In Japan

- 1980's~ Large Scale Integrated Circuits (LSI) Industries
- 1991 Carbon Nanotube discovered by Dr. Iijima
- 2000 The National Nanotechnology Initiative (NNI) in USA
- 2000 Working group of Nanotechnology launched by Nippon Keidanren (Japan Federation of Economic Organizations)
- 2001 The future society created Nanotechnology <n-Plan21>
- 2002 Nanotechnology Researchers Network Center (MEXT)
 Effective support to "*MEXT Nanotechnology Support Project*".
 MEXT: (Ministry of Education, Culture, Sports, Science and Technology)

The national budget has been mainly distributed through Japan Science and Technology Agency (JST).

The future society created nanotechnology <n-Plan21> Outline March 27, 2001 Japan Federation of Economic Organizations (Keidanren)



Two main researchers of Nano-photonics in Japan



Professor Motoichi Ohtsu:

University of Tokyo

Professor Satoshi Kawata:

Osaka University

RIKEN (The Institute of Physical and Chemical Research)



Japan Science and Technology Agency (JST)

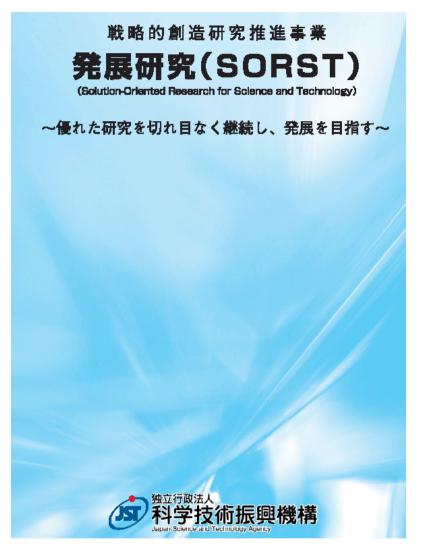
The aim of JST is to establish Japan as a nation built on the creativity of science and technology.

32.31	Project Research Groups and Locations			
Announcement	Ohtsu Localized Photon Project (Tokyo)			
and the second of the second of the	Theory Group	Tenko Bldg. (Machida)		
In Outline of ERATO	Nano-Photonics Group	Tenko Bldg. (Machida)		
and the second second second	Atom-Photonics Group	Tenko Bldg. (Machida)		
an Outline of Project	Kitano Symbiotic Systems Project (ToKyo)			
An Outline of Post-Project Pluse	Systems Biology Group	Mansion 31 (Tokyo)		
- urchinik of rost rojett rink	Symbiotic Intelligence	Mansion 31 (Tokyo)		
ERATO Laboratory Sites-	Group	Caltech (California)		
Project Research Groups	Kusumi Membrane Organizer Project (Nagoya)			
and Locations	Molecular Interaction Group	Kumazaki Bldg. (Nagoya)		
- Caller	Membrane Skeleton Function Group	Kumazaki Bldg. (Nagoya)		
TOP	Cell-Cell Interation Group	Kumazaki Bldg. (Nagoya)		
☑Contact Us 日本語	Kondoh Differentiation	Signaling Project (Kyolo)		
	Cell Interactions Group	Kinki Invention Center (Kvoto)		
	Developmental Mutants Group	Kinki Invention Center (Kyoto)		
Constant States	Differentiation Transition Group	Kinki Invention Center (Kyoto)		
	Tarucha Mesoscopic Correlation Project (Atsugi, Kanagawa)			
	Supoerstructure Correlation Research Group	NTT-Atsugi Research Development Center		
	Heteroo-system Correlation Research Group	NTT-Atsugi Research Development Center		
	Quantum Transport Research Group	Delft University of Technology (Holland)		

ERATO-type (Exploratory Research for Advanced Technology)

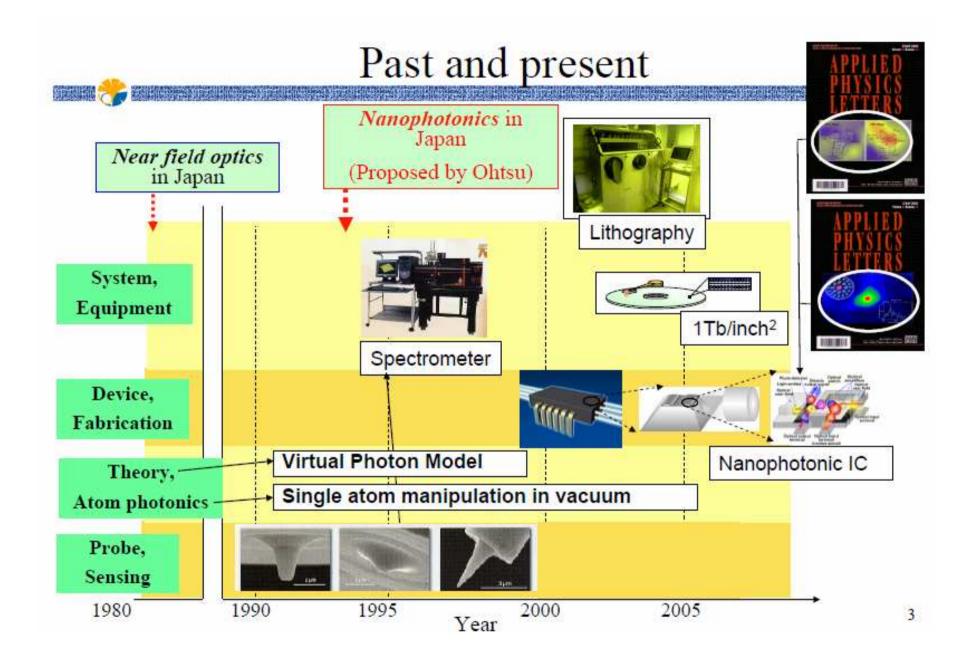
Localized Photon Project, (1998-2003), \$8.3 million,

Project Leader: *Prof. M. Ohtsu* (Tokyo University)



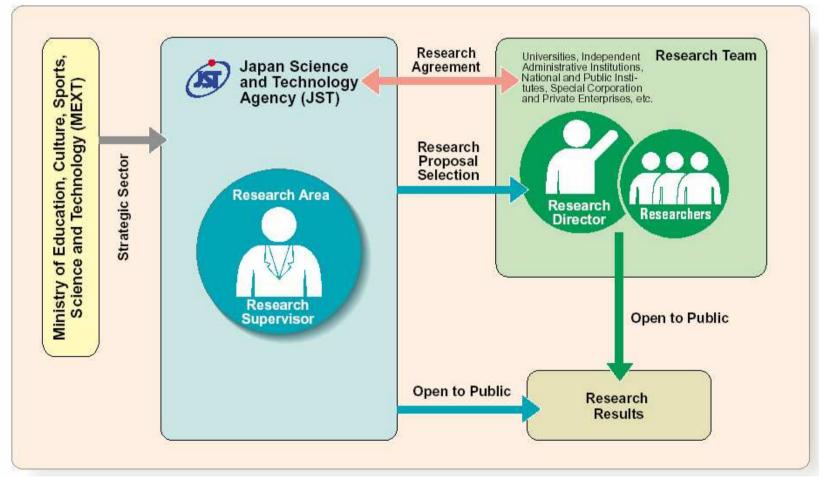
SORST-type (Solution-Oriented Research for Science and Technology). Research projects of the SORST program are selected among projects with high expectations of outstanding results and of extraordinary developments in CREST-type, ERATO-type and other projects. Above *Localized Photon Project* has been selected as the following project:

Nanophotonics Team, (2003-2008), \$2.5 million, Project Leader: Prof. M. Ohtsu (Tokyo University)



Outline of CREST

After proposal invitation and selection, JST promotes the basic research by concluding Research Agreements with the research institutes which researchers belong to.



CREST-type

(Core Research for Evolutional Science and Technology: Team type research)

FY2006

Plasmonic Scanning Analytical Microscope

Satoshi Kawata

Professor, Osaka University

We propose to develop a new analytical nanoscope that uses surface plasmon polaritons (SPPs) as a nano-probe. SPPs are collective oscillation of electrons excited locally in metal nano structures. Our microscopy uses 1) locally enhanced electromagnetic field provided by SPPs and 2) perturbation of optical responses induced by the mechanical interactions between the probe and the sample with typical probe-applied force of the order of nano-Newton, which enables one to perform nano-analysis and imaging of nano-materials.

Studies of Semiconductor Quantum Structures and Exploration of Terahertz Technology

Susumu Komiyama

Professor, The University of Tokyo

A sensitive passive method of detecting extremely weak terahertz waves emitted from objects without external illumination is developped by ingeniously exploiting semiconductor quantum structures. Beyond characterization of matters, the method makes it possible to investigate phenomena and their duporties in the chiest. The method will encour a widecerced

Development of Laser assist Three-dimensional Atom Pro Applications for Device Anal

Kazuhiro Hono

Fellow, National Institut

To broaden the applications of the thr probe (3DAP) technique for mapping re tions for a wide variety of materials, th of the conventional 3DAP that stem fror process will be overcome by using puls evaporation. A newly developed lase 3DAP will be applied to nanostructure and semiconductor materials and their metallic materials that used to be impor the voltage pulsed 3DAP. At the same t ration techniques that will make it possi areas of various types of materials will

Development of a Multi-func Sum Frequency Microscope

Goro Mizutani

Professor, Japan Advanced Institute of S

When a medium is irradiated with light frequencies, it radiates another light f quency. In an optical sum frequency light field is focused on a two-dimensior

Creation and simulation of optoelectronics function in nanometer space



Hirokazu Hori

University of Yamanashi, Professor

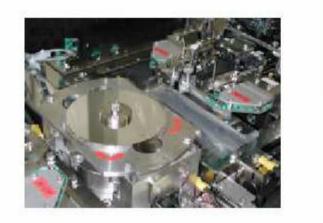
Website of Lab

This research is aiming at creation of nano-photonics devices for innovative information processing and signal transfer systems by means of controlling coupled system of electrons with optical fields in nanometer-sized space. Simulation is developed for design and analysis of optoelectronic processes in spin-chain-controlled nanophotonics device and its fabrication processes by nano-photolithography. Based on experimental research of atomic/molecular level, this project will open up new field of nano-optoelectronics.

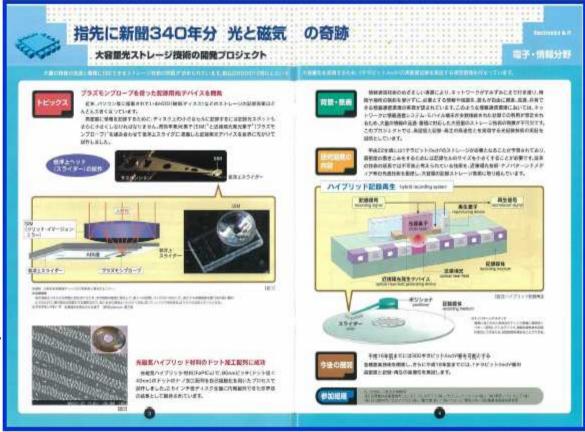
Main Research Collaborators list

Shinichi Oishi	Waseda University	Faculty of Science and Engineering	Professor
Kiyoshi Kobayashi	Tokyo Institute of Technology	Graduate School of Science and Engineering	Professor
Makoto Naruse	National Institute of Information and Communications Technology	Photonic Network Group	Senior Principle Investigators
Kazuo Kitahara	International Christian University	Division of Natural Sciences, College of Liberal Arts	Professor
Masaru Tsukada	Waseda University	Faculty of Science and Engineering	Professor
Hitoshi Nejoh	National Institute for Materials Science	Nano System Architecture Group, Nano System Function Center	Senior Principle Investigators

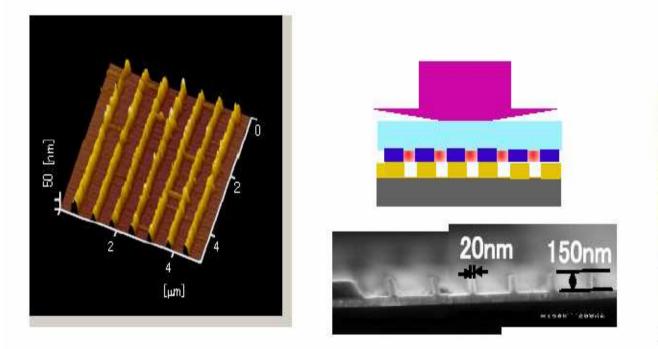
Ultrahigh Capacity Storage Technology Project, Ministry of Economy, Trade & Industry (METI) (2003-2007), 26 M USD (Hitachi, Toshiba, Fujitsu, Ricoh, SII, Hitachi-Maxell, Konica-Minolta, Pioneer)



Exhibited at International Trade Expo 2005



Near field optical lithography, Ministry of Education (2005-2007), 2.5 M USD (Canon)

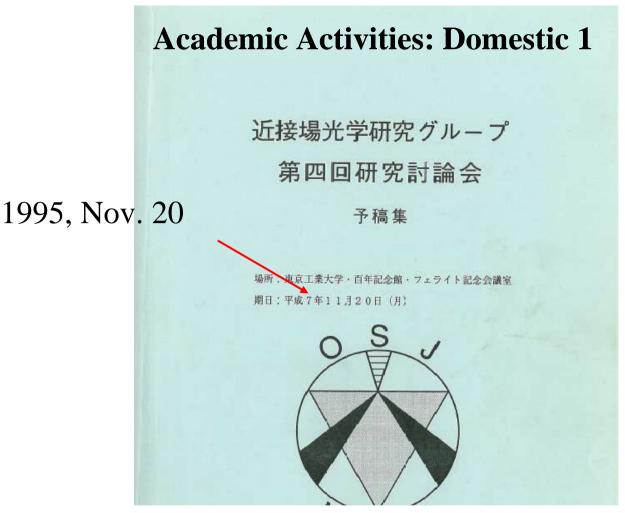


Proto-type of a commercial product



Resolution 20- 50 nm (5mm)

1m x 1m x 1m



Technical group of Optical Near-Fields in Optical Society of Japan and Japan Society of Applied Physics. This group has organized symposium every year for 1994-2004.

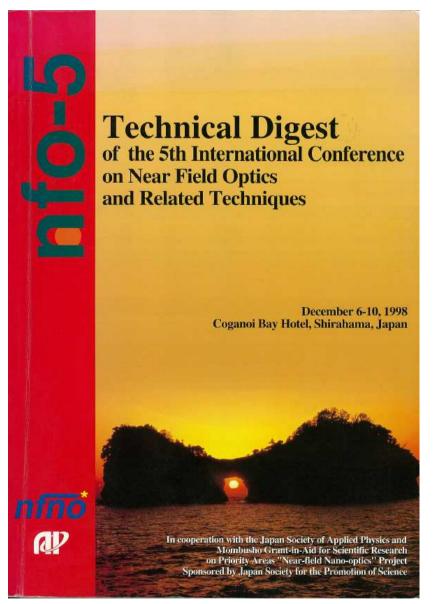
The group has changed name as *Technical Group of Nano-Optics* in 2004 and has organizes symposium every year since 2004.

Academic Activities: Domestic 2



Plasmonics Symposium in Japan Society of Applied Physics. This symposium has been held every year since 2003.

Academic Activities: International 1



Academic Activities: International 2

http://www.nano-optics.jp/apnfo5/



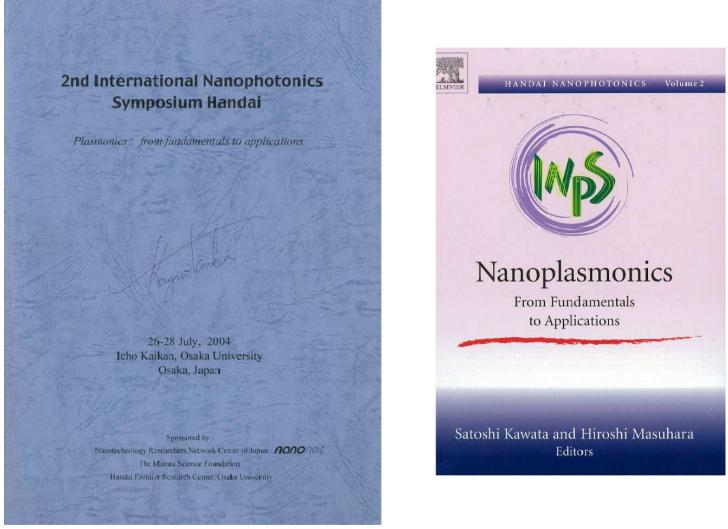
ABSTRACTS OF

The 5th Asia-Pacific Conference on Near-Field Optics

November 15-17, 2005 TOKI MESSE, Niigata Convention Center Niigata, Japan

Asia Pacific Workshop on Near Field Optics (APNFO): This workshop has been held from 1996 to present in following places: 1st: Seoul, 2nd: Beijing, 3rd: Melbourne, 4th: Taroko, 5th: Niigata, 6th:Yellow Mountain.

Academic Activities: International 3



The International Nanophotonics Symposium Handai (INSH): This symposium has been held in 2004 and 2006 at Osaka University (Japanese name HANDAI).

Topics of Nano-photonics in Japan 1

Appl. Phys. B 84, 243-246 (2006)

DOI: 10.1007/s00340-006-2234-x

Applied Physics B Lasers and Optics

T. KAWAZOE^{1,™} K. KOBAYASHI² K. AKAHANE³ M. NARUSE³ N. YAMAMOTO³ M. OHTSU^{1,4}

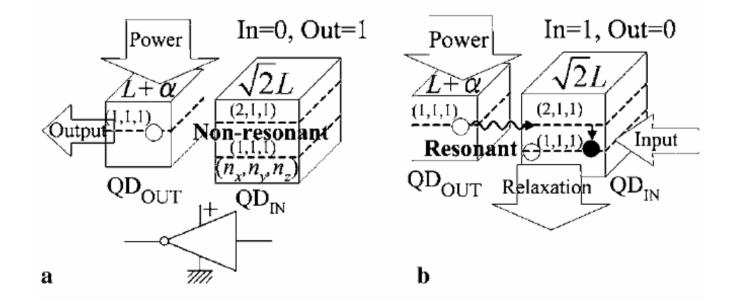
Demonstration of nanophotonic NOT gate using near-field optically coupled quantum dots

¹ Japan Science and Technology Agency, Machida, Tokyo 194-0004, Japan

² Department of Physics, Tokyo Institute of Technology, Meguro-ku, Tokyo 152-8551, Japan

³ National Institute of Information and Communications Technology, Koganei, Tokyo 184-8795, Japan

⁴ Department of Electronics Engineering, University of Tokyo, Bunkyo-ku, Tokyo 113-8656, Japan



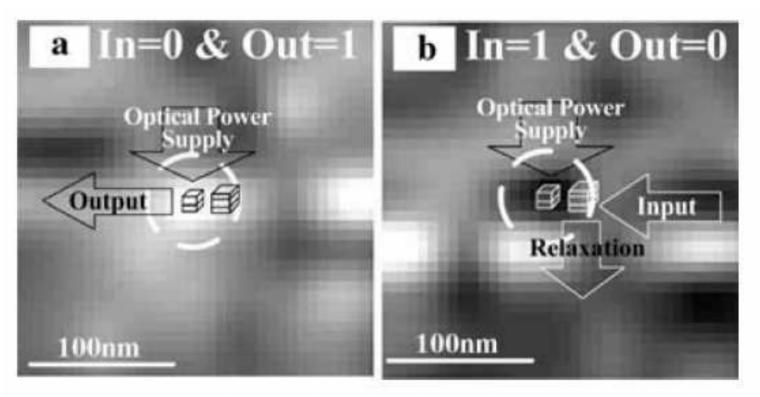
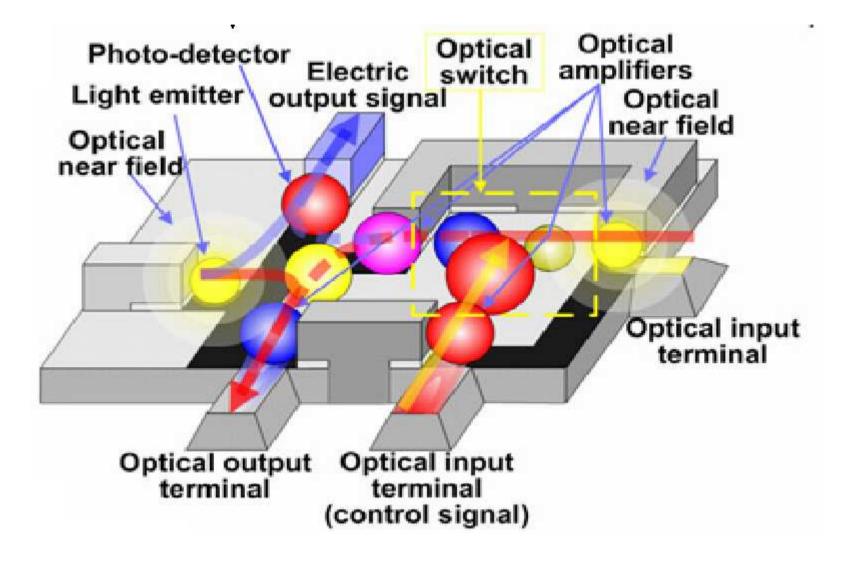


FIGURE 2 The spatial distribution of the output signal from a nanophotonic NOT gate measured using a near-field microscope at Input = 0 (a) and Input = 1 (b)

Future Nanophotonic Integrated Circuits proposed by Ohtsu's Group



Topics of Nano-photonics in Japan 2

Signal Characteristics of Super-Resolution Near-Field Structure Disk in Blue Laser System

Jooho Kim^{*}, Inoh Hwang, Hyunki Kim, Duseop Yoon, Insik Park, Dongho Shin, Yunchang Park¹ and <u>Junji Tominag</u>a²

Digital Media R&D Center, SAMSUNG ELECTRONICS CO., LTD, Suwon 442-742, Korea ¹Analytical Engineering Center, Samsung Advanced Institute of Technology, Kihung, Yongin 449-712, Korea

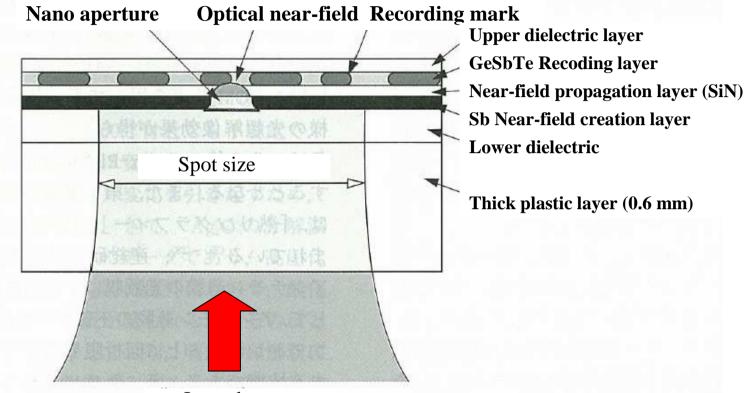
²Center for Applied Near-Field Optics Research, National Institute of Advanced Industrial Science and Technology (AIST), Tsukuba 305-8563, Japan

(Received December 8, 2003; accepted February 17, 2004; published July 29, 2004)

Abstract:

We report the signal characteristics of a <u>super-resolution near-field structure (super-RENS)</u> disk in a blue laser system (laser wavelength, 405 nm; numerical aperture (NA), 0.85). By introducing a new structure for the blue laser system, a 42.5 dB carrier to noise ratio (CNR) at a 50-nm-mark-length-signal (which is equivalent to a 75 GB capacity with a 0.32 micrometer track pitch and a 1–7 modulation code (Blu-ray disc (BD) format)) and a much higher readout-stability were obtained. Transmission electron inicroscope (TEM) image analysis revealed that the new blue structure has clear diffusion protection barriers produced by continuous Pt particles, which is related to higher CNR and readout stability characteristics.

First Generation Super-RENS



Laser beam

図1 第1世代 Super-RENS 光ディスクの構造 Sb 近接場光発生層/近接場光伝搬
 層/GeSbTe 記録層を特に Super-RENS 機能層と呼ぶ.レーザは基板を透かして入射され,Sb 層に発生する光学的微小開口で絞られるが,このとき近接場光が発生する.
 近接場光は SiN でできた伝搬層(厚さ 20 ~ 40nm)を透かして記録層に記録された結晶-アモルファスの情報パターンを読み出す.Super-RENS 光ディスクは,約800 ~ 2,400rpm で回転する.

Topics of Nano-photonics in Japan 3

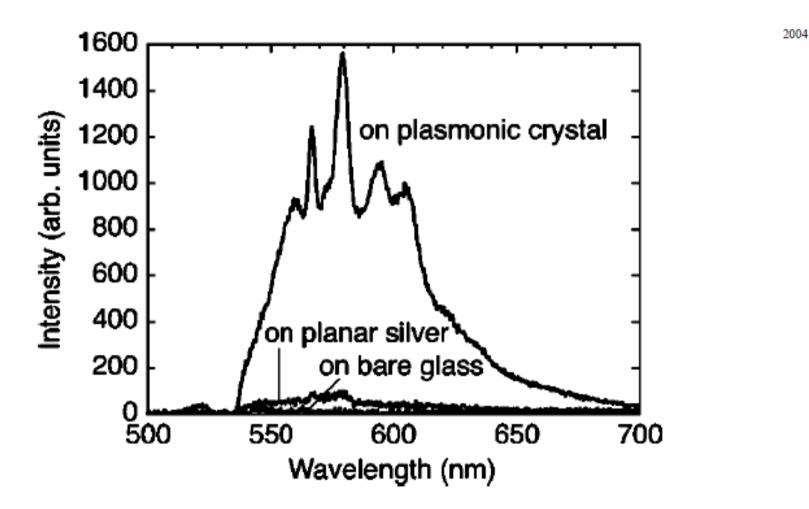


FIG. 3. Fluorescence spectra of a methyl-red doped PMMA film deposited on a bare glass substrate, on a planar silver surface, and on a 507 nm pitch plasmonic crystal.

Topics of Nano-photonics in Japan 4 Simulation of practical nanometric optical circuits based on surface plasmon polariton gap waveguides

Kazuo Tanaka, Masahiro Tanaka, and Tatsuhiko Sugiyama

Department of Electronics and Computer Engineering, Gifu University, Yanagido 1-1, Gifu City, Japan 501-1193 <u>tanaka@tnk.info.gifu-u.ac.jp</u>

Abstract: The feasibility of nanometric practical optical waveguide circuits based on surface plasmon polariton gap waveguides (SPGWs) is investigated in detail through three-dimensional simulations. H-plane planar branching waveguide circuits of subwavelength scale are shown to be possible using SPGWs. The waveguide characteristics of the circuits are found to be highly sensitive to the dimensions of the optical circuit, indicating that highly accurate computer-aided design and simulations are necessary for the construction of practical SPGW-based optical circuits.

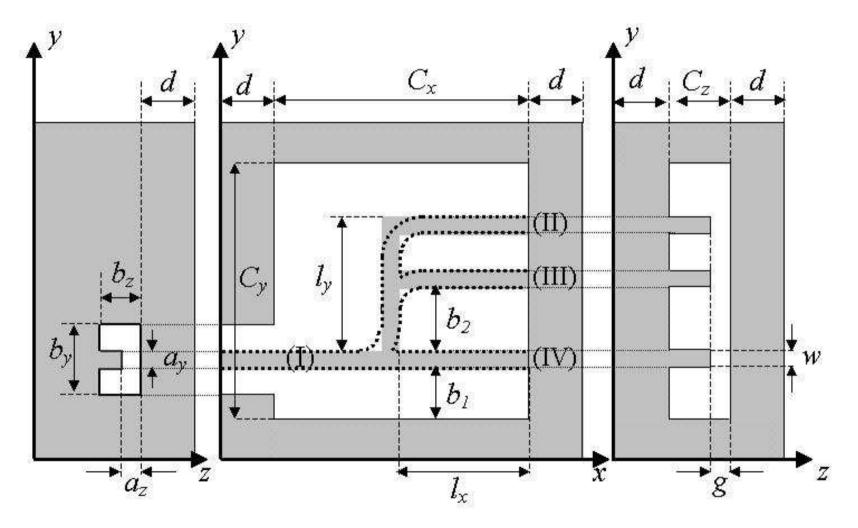
©2005 Optical Society of America

OCIS codes: (240.6680) Surface plasmons; (250.5300) Photonic integrated circuits; (000.4430) Numerical approximation and analysis

References and Links

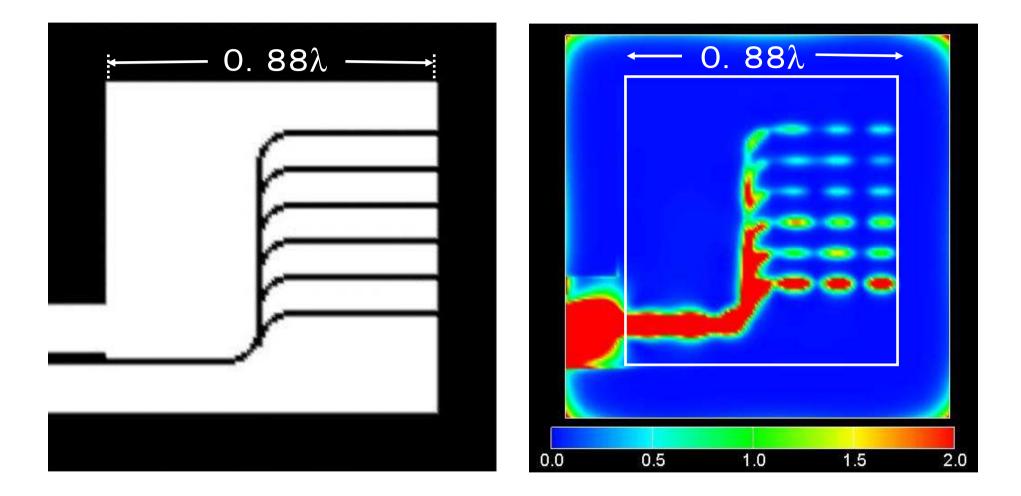
Simulation of practical nanometric optical circuits based on surface plasmon polariton gap waveguide, *Optics Express* **13**, 256-266 (2005)

Nanometric optical circuits using Surface Plasmon Polariton



 λ = 573 nm, ε_1 = -12.4 – *j*0.85 (Silver) ε_2 = 2.25 (Free space)

Dense and Complicated Nanometric Optical Circuits



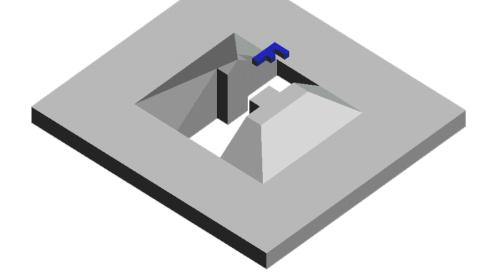
Simulation of practical nanometric optical circuits based on surface plasmon polariton gap waveguide, *Optics Express* **13**, 256-266 (2005)

Metallic tip probe providing high intensity and small spot size with a small background light in near-field optics

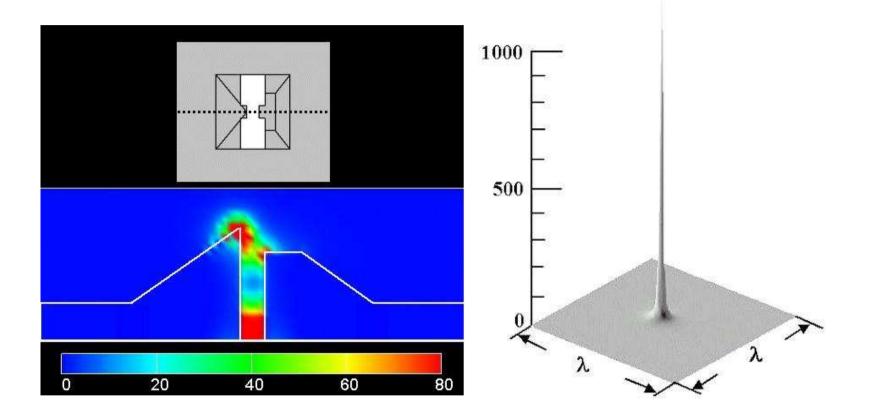
Kazuo Tanaka,^{a)} Masahiro Tanaka, and Tatsuhiko Sugiyama Department of Electronics and Computer Engineering, Gifu University, Yanagido 1-1, Gifu, Japan 501-1193

(Received 16 December 2004; accepted 22 August 2005; published online 7 October 2005)

A metallic tip probe that gives high optical intensity and small spot size with a small background light is proposed and simulated. The proposed tip probe provides advantages of both the aperture probe and the apertureless probe currently used in the scanning near-field optical microscope. The tip probe is illuminated by surface plasmon polaritons transmitted through the I-shaped aperture in a pyramidal structure on a thick metallic screen. Scattering of optical waves by this structure is solved numerically using a volume integral equation by generalized conjugate residual iteration and fast Fourier transformation. The proposed tip probe is shown to simultaneously provide both high near-field intensity and small spot size with a small background light. © 2005 American Institute of Physics. [DOI: 10.

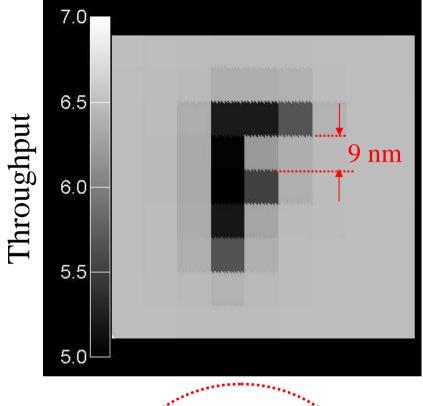


Creation of strongly localized and strongly enhanced optical near-field on metallic probe-tip with surface plasmon polaritons, *Optics Express* **14**, 832-846 (2006)

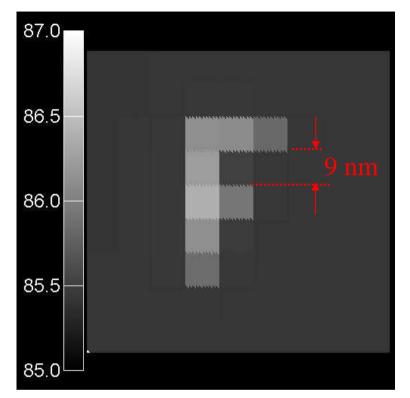


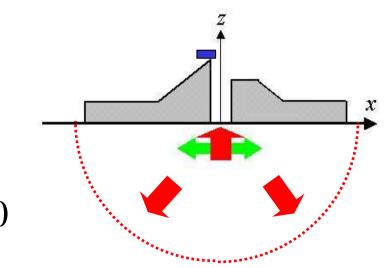
 λ = 573 nm, ε_1 = -12.4 – *j*0.85 (Silver) ε_2 = 2.25 (Free space)

Illumination mode

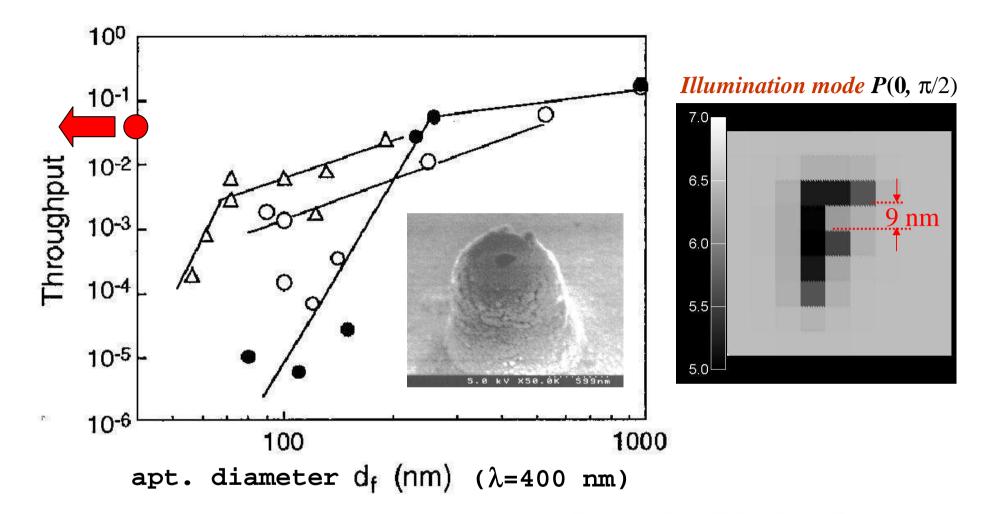


Collection-reflection mode





 $k_0 d=0$



M. Ohtsu (Ed.),

Near-Field Nano/Atom Optics and Technology, Springer 1998

Conclusions

Modern electrical and electronics technologies are used in the space whose size is much smaller than the electromagnetic wavelength.

Similarly, it will be possible to use optical technologies in the space whose size is much smaller than the optical wavelength in the near future.

In this meaning, *Nano-photonics* are interesting and important subjects from not only technological view points but also view points of fundamental physics

e

In Jap *Thank you for your attention*. technology of *Nano-photonics* and are now doing research.

Furthermore, many interesting ideas are proposed by Japanese researchers.

Unfortunately, only a small number of commercial products using *Nano-photonics* technology have emerged in the market until now.

I hope that Japan will be able to make large contribution to *Nano-photonics* in the future.

Topics of Nano-photonics in Japan 3

APPLIED PHYSICS LETTERS 87, 043112 (2005)

Local density of states mapping of a field-induced quantum dot by near-field photoluminescence microscopy

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International Research Center for Elements Science, Institute for Chemical Research, Kyoto University, Uji, Kyoto 611-0011, Japan, Kanagawa Academy of Science and Technology, 3-2-1 Sakado, Kawasaki 213-0012, Japan, and Nanostructure and Material Property, PRESTO, Japan Science and Technology Agency, 4-1-8 Honcho, Saitama 332-0012, Japan

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S. Nomura

Institute of Physics, University of Tsukuba, 1-1-1 Tennoudai, Tsukuba, Ibaraki 305-8571, Japan and CREST, Japan Science and Technology Agency, 4-1-8 Honcho, Saitama 332-0012, Japan

Y. Aoyagi

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(Received 14 February 2005; accepted 23 May 2005; published online 20 July 2005)

We have described near-field photoluminescence microscopy of a field-induced quantum-dot structure based on a Be– δ -doped GaAs–Al_{1-x}Ga_xAs single heterojunction with a surface square mesh gate. The local density of states in the field-induced quantum dot was mapped by measuring the spatial distribution of the near-field photoluminescence intensity, because the photoluminescence spectrum owing to the recombination of holes bound to Be accepters with electrons in an electron gas contains information on the electronic density of states. Experimentally, we observed that the electrons confined in lower energy states spatially localize in a field-induced quantum dot. © 2005 American Institute of Physics. [DOI: 10.1063/1.1984095]

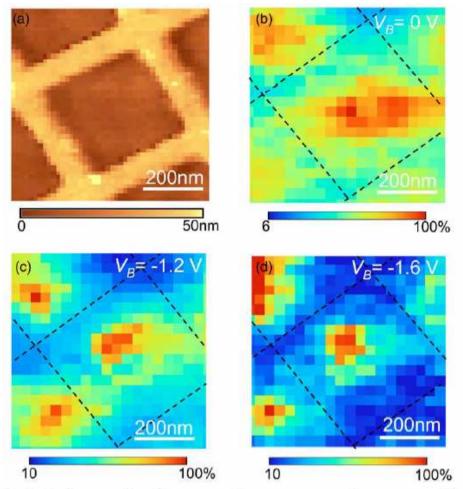
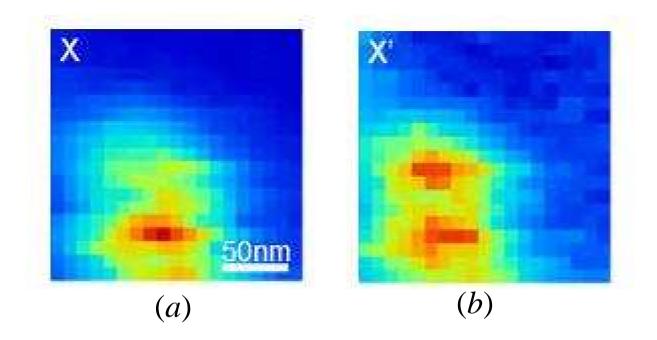


FIG. 2. (Color) (a) Atomic force microscopy image of the gated sample surface. (b)–(d) Near-field PL images at different external bias-voltages $(V_B=0, -1.2, \text{ and } -1.6 \text{ V}, \text{ respectively})$. These images were monitored at a detection energy of around 1.483 eV at 9 K. The dotted lines in the images correspond to the positions of the surface gate. The scanning area of these images was $775 \times 775 \text{ nm}$. (e) Near-field PL image at $V_B=-1.6 \text{ V}$, measured for a wide area of $1100 \times 1100 \text{ nm}$. The images in (b)–(d) were of the squared dotted area. (f) Cross-sectional PL intensity profile, taken along a diagonal of the mesh gate.



Mapping of wave functions inside quantum dots by near-field microscopy. The resolution is 30 nm.(*a*) Ground state (b) Excited state.

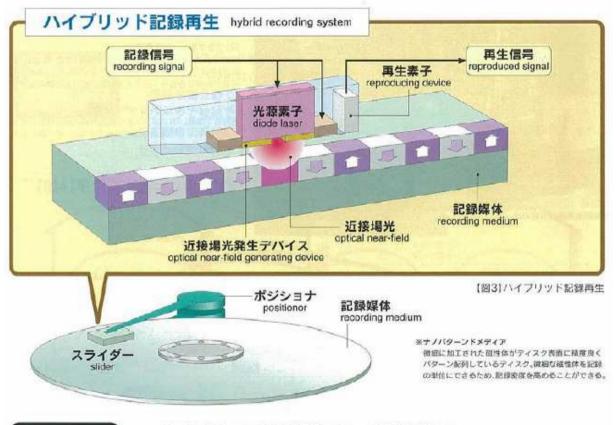


情報通信技術のめざましい進展により、ネットワークがすみずみにまで行き渡り、時 間や場所の制約を受けずに、必要とする情報や知識を、誰もが自由に創造、流通、共有で きる情報通信環境の実現が望まれています。このような情報通信環境においては、ネッ トワークに情報通信システム・モバイル端末が多数接続された状態での利用が想定され るため、大量の情報の流通・蓄積に対応した大容量のストレージ技術の発展が不可欠です。 このプロジェクトでは、高密度と記録・再生の高速性とを実現する光記録技術の実証を 目的としています。



今後の展開

平成22年頃には1テラビット/inch²のストレージが必要となることが予想されており、 高密度の書きこみをするためには記録セルのサイズを小さくすることが必要です。従来 の技術の延長では不可能と考えられている技術を、近接場光技術・ナノバターンドメデ ィア等の先進技術を駆使し、大容量の記録ストレージ実現に取り組んでいます。

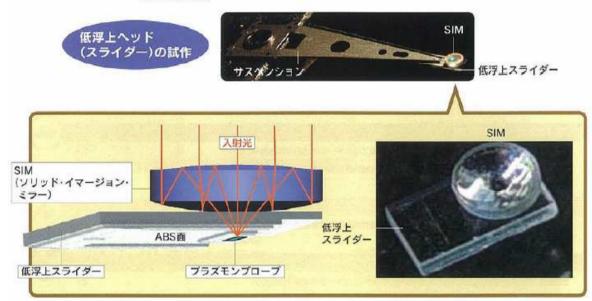


平成16年度までには300ギガビット/inch²級を可能とする 各種要素技術を開発し、さらに平成18年度までには、1テラビット/inch²級の 高密度と記録・再生の高速性を実証します。 トピックス

プラズモンプローブを使った記録用光デバイスを開発

近年、パソコン等に搭載されているHDD(磁気ディスク)などのストレージの記録容量はど んどん大きくなっています。

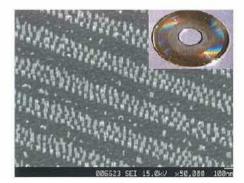
高密度に情報を記録するために、ディスク上の小さなセルに記録するには記録光スボットも さらに小さくしなければなりません。高効率集光素子(SIM)[#]と近接場光発光素子[#](プラズモ ンプロープ)^{*}を組み合わせて低浮上スライダに搭載した記録用光デバイスを世界に先がけて 試作しました。



※SIM 入時光を近接頃のヘッドまで効率員く集光するミラー。

派匠接場光

先の波長よりも小さな物質に先を当てたとき、その物質の表面に発生して、這くへは伝搬していかない光のこと。あたかも物質表面を覆う光の味い袋の ようなもので、酸の厚みは物質の寸法復度なので、当てる光の溶長よりも小さくなる。従って、レンズで光を投るよりも小さな光スポットとなる。 ※プラズモンブローブ 近接場光を発光させる裏子 [参考]plasmon:電子波



光磁気ハイブリッド材料のドット加工配列に成功

光磁気ハイブリット材料(FePtCu)で、80nmピッチ(ドット径< 40nm)のドットのナノ加工配列を自己組織化を用いたプロセスで 試作しました。2.5インチ径ディスク全面に円周配列できた世界初 の成果として期待されています。

【図1】

Research Area

Virtual Lab in Nanotechnology Area

Creation of Nanodevices and Sys Phenomena and Functional Princ

Research Supervisor: Dr. Koji Kajimura

(Vice President, Japan Society for the Promotion

FY2001

Development of Fundamental Technology for Spin Quantum Dot Memories

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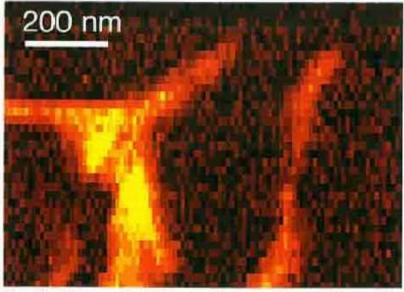
This research aims at the creation of spin quantum dot memories based on a novel concept. The essential part of the research is to demonstrate the spin-dependent Coulomb blockade effect due to single electron tunneling at room temperature in ordered magnetic nano dots, in which the tunneling magnetoresistance can be controlled by applying a voltage. We will develop novel materials or structures to achieve enhanced tunneling magnetoresistance and thus large signal voltage. In addition, the fabrication technology to create twodimensional array of dots and new memory devices will also be developed. We anticipate, at the end of this research, the creation of terabits non-volatile memories and new spread of spintronic devices.

Nonlinear Nano-Photonics

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Marvelous novel functions that are not accessible by conventional nanotechnologies are expected if photons are utilized for sensing, manipulating, and processing 'eatures at nanoscale. In this research, we will combine the concepts of near-filed optics and non-linear optics, conducting fundamental research on nonlinear nanophotonics and pushing it for practical applications. Of particular interest is applying femtosecond lasers to plasmon field-enhanced technologies for nano-spectroscopy and nano-devices.



An optical image of a DNA network nano-structure obtained by the combination of near-field optics and nonlinear spectroscopy. The distribution of adenine base molecules, one of the DNA bases, is visualized.

Towards plasmonic band gap laser

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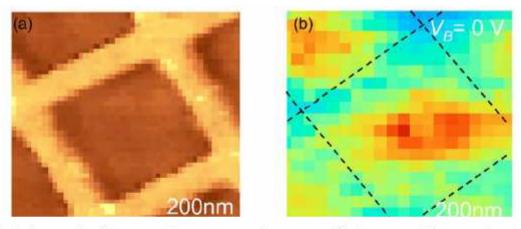
(Received 19 April 2004; accepted 7 September 2004)

A two-dimensional periodically corrugated silver surface prohibits the propagation of the surface plasmons in all lateral directions. And band gaps are generated in the dispersion relation, named plasmonic band gaps. At the edge of this band gap, surface plasmons are laterally confined as standing waves. We investigate this phenomenon for lasing action by the use of a dye film deposited on a corrugated silver surface. Fluorescence of the dye was strongly enhanced. Indeed, we obtained an enhancement factor 150 for a methyl-red doped poly (methylmethacrylate) film and 3 for an evaporated 4-dicyanomethylene-2-methyl-6-p-dimethyl-aminostyryl-4H-pyran film. We also discuss the conditions under which lasing action may occur. ©2004 American Institute of *Physics*

1. ナノプラズモニクス (岡本, H'Dhili^{*1}, Feng^{*1}, Simonen^{*2}, 奈良岡^{*1}, 井田^{*3})

プラズモニック結晶は金属表面に二次元表面レリーフ格 子を刻むことによって光子を三次元的に閉じこめる構造で ある。プラズモニック結晶における輻射特性をフーリエモー ダル法を用いて解析した。その結果,格子の形状をデザイ ンすることにより,輻射特性を制御できることが分かった。 また,金属として薄膜を用いることで両界面の表面プラズ モンの相互作用により,吸収損失が低減できることが分かっ た。さらに,実際に色素薄膜を堆積したプラズモニック結 晶を作製し,その光学特性を測定した。陰極としてプラズ モニック結晶を用いることで,高効率の上面発光が得られ る有機 EL 素子を開発した。 1. ナノブラズモニクス (岡本, H'Dhili^{*1}, Feng^{*1}, 柳 沢^{*2})

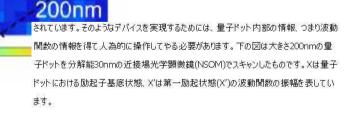
表面プラズモン共鳴と二次元フォトニッククリスタルを 組み合わせたプラズモニック結晶の吸収スペクトルおよび その上に堆積した色素膜からの蛍光スペクトルを観測し、そ の光学特性の解析を行った。また、プラズモニック結晶を 用いたレーザー発振の可能性について検討した。プラズモ ニック結晶を電極として用いた有機 EL 素子を作製し、そ の発光スペクトルの角度依存性から、素子の光学特性を解 析した。本素子の外部発光効率は、プラズモニック結晶を 用いない場合と比較して 10 倍向上した。

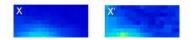


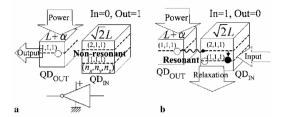
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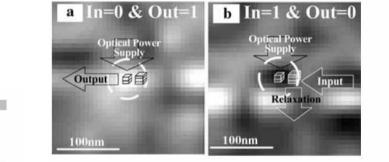
FIG. 2. (Color) (a) Atomic force microscopy image of the gated sample surface. (b)–(d) Near-field PL images at different external bias-voltages $V_B=0, -1.2, \text{ and } -1.6 \text{ V}$, respectively). These images were monitored at a detection energy of around 1.483 eV at 9 K. The dotted lines in the images correspond to the positions of the surface gate. The scanning area of these images was 775×775 nm. (e) Near-field PL image at $V_B=-1.6$ V, measured for a wide area of 1100×1100 nm. The images in (b)–(d) were of the squared dotted area. (f) Cross-sectional PL intensity profile, taken along a diagonal of the mesh gate.

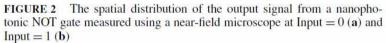


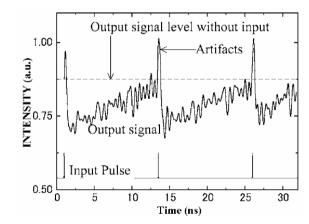












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Appl. Phys. B 84, 243-246 (2006)

DOI: 10.1007/s00340-006-2234-x

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Demonstration of nanophotonic NOT gate using near-field optically coupled quantum dots

Applied Physics B

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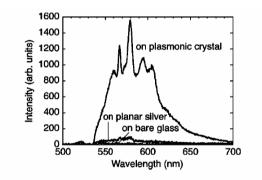


FIG. 3. Fluorescence spectra of a methyl-red doped PMMA film deposited on a bare glass substrate, on a planar silver surface, and on a 507 nm pitch plasmonic crystal.